

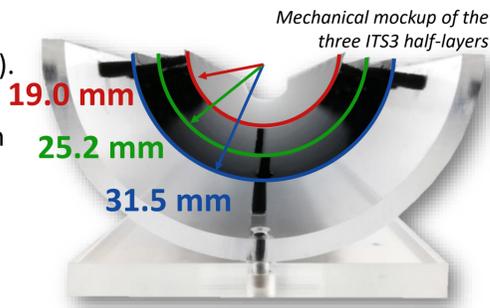
Characterization results of MAPS digital prototypes for the ALICE ITS3

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The ALICE Inner Tracking System for LHC Run 4

- A new Inner Tracking System ITS3 [1] will replace the innermost layers of the ALICE ITS2 during LHC Long Shutdown 3 (2026-2028).
- Tracking efficiency and pointing resolution will be further improved by this upgrade, thus allowing to increase the precision of measurements in the heavy-flavour sector and to bring another set of fundamental observables into reach [2], e.g.:
 - B_s^0 and Λ_b^0 at low transverse momenta
 - Non-prompt D_s^+ and Ξ_c^+ decays in heavy-ion collisions



Detector layout:

- 3 truly cylindrical self-supporting layers
- Each half-layer made by 1 flexible MAPS sensor which:
 - has a large-area $O(10 \times 26 \text{ cm}^2)$
 - is ultra-thin ($\leq 50 \mu\text{m}$)
- Ultra-light carbon foam support structures keep in position the sensors
- Innermost layer at 19 mm from the interaction point
- Unprecedentedly low material budget of $0.09\% X_0/\text{layer}$
- Air cooling system

• Talk by L. Aglietta

1. ITS3 MAPS prototypes

The Tower Partners Semiconductor Co. [3] 65 nm CMOS imaging process for MAPS was chosen for the ALICE ITS3. Key advantages:

- High radiation hardness
- Low power consumption
- 5 μm 2D spatial resolution
- Large wafers ($\varnothing 300 \text{ mm}$)

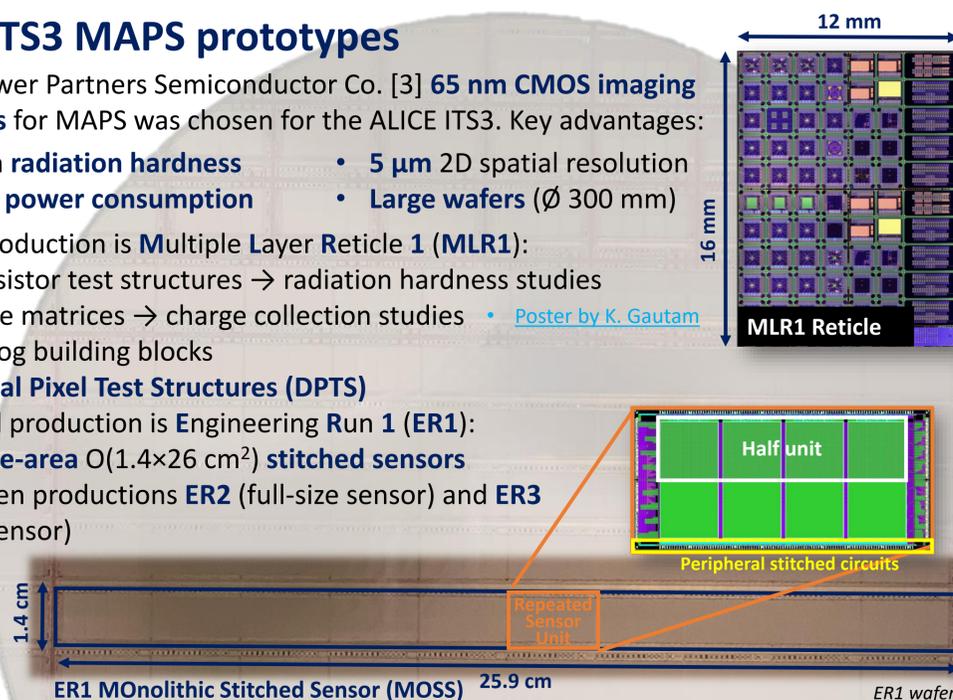
First production is Multiple Layer Reticle 1 (MLR1):

- Transistor test structures \rightarrow radiation hardness studies
- Diode matrices \rightarrow charge collection studies
- Analog building blocks

• Digital Pixel Test Structures (DPTS)

Second production is Engineering Run 1 (ER1):

- Large-area $O(1.4 \times 26 \text{ cm}^2)$ stitched sensors
- Foreseen productions ER2 (full-size sensor) and ER3 (final sensor)



2. MLR1 and ER1 digital pixel architecture

- 50 μm thick sensor
- Variable pixel pitch $O(20 \mu\text{m})$
- Additional low dose n-type implant allows to deplete the epitaxial layer over the full width:

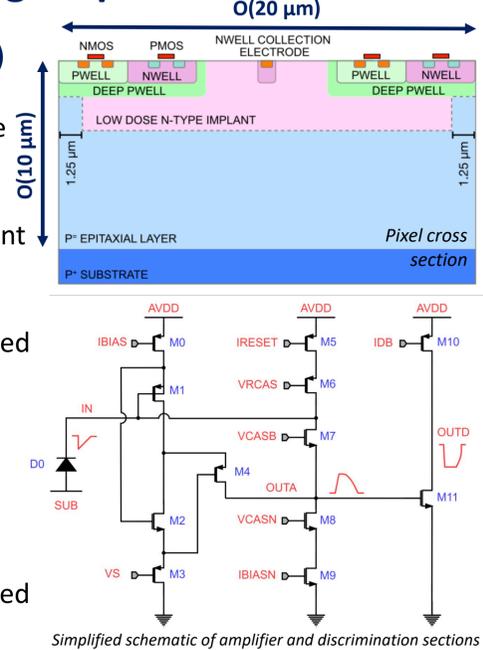
- \rightarrow Faster and more efficient charge collection
- \rightarrow Less charge sharing

The pixel architecture has evolved from ITS2 ALPIDE sensor [4].

Each pixel hosts:

- Sensing diode
- Front-end amplifier
- Discriminator
- Digital pixel section

Similar architecture will be ported to the final sensor design.

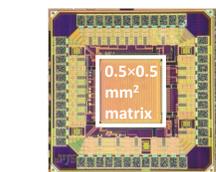


3. Energy loss measurements with DPTS

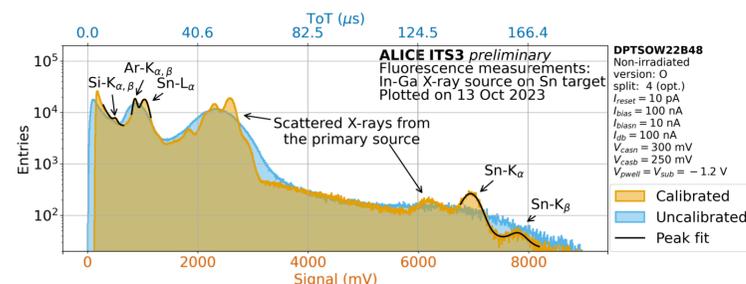
The DPTS is a $1.5 \times 1.5 \text{ mm}^2$ MLR1 chip:

- 32x32 pixel matrix, 15 μm pitch
- Time-over-threshold (ToT) measurements

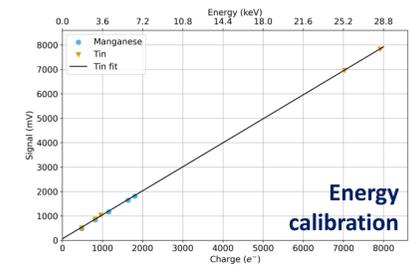
The linearity of the front-end from 1.7 to 28.5 keV was evaluated with fluorescence X-ray measurements. A Mn foil and a Sn foil were used as targets.



DPTS Goal: study the in-pixel front-end



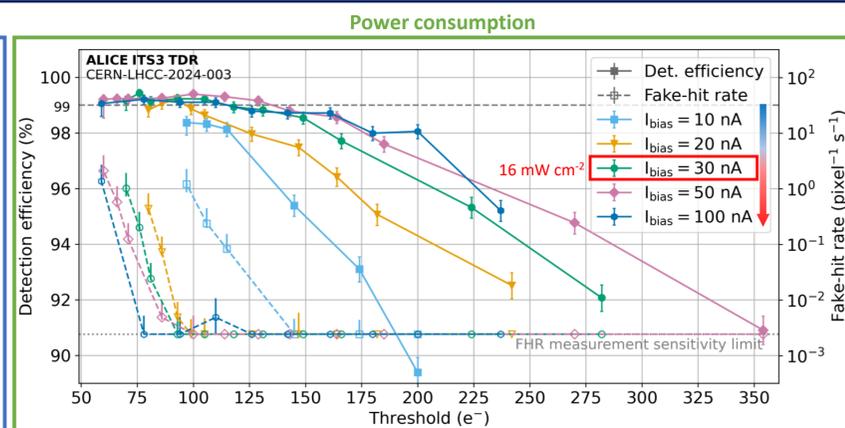
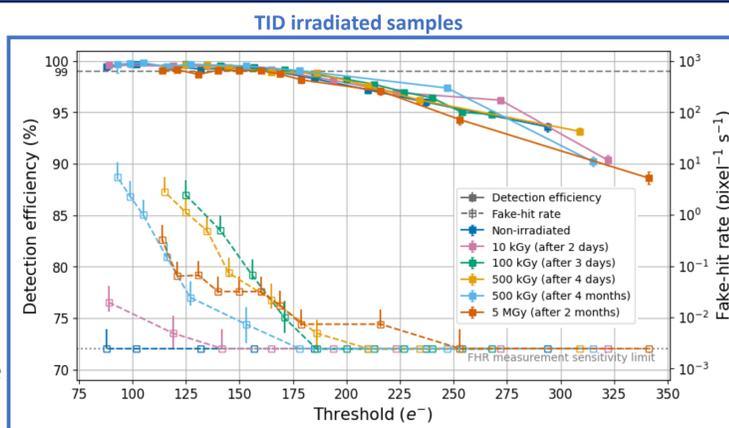
- Good agreement between Sn and Mn data
- Demonstrated linearity of the response up to 28.5 keV



4. DPTS in-beam measurements

Measurements to assess [5]:

- Detection efficiency and spatial resolution
- Irradiated samples show excellent detection efficiency (99%)
- DPTS power consumption can be lowered to 16 mW cm^{-2}



5. Large-area stitched sensor characterization

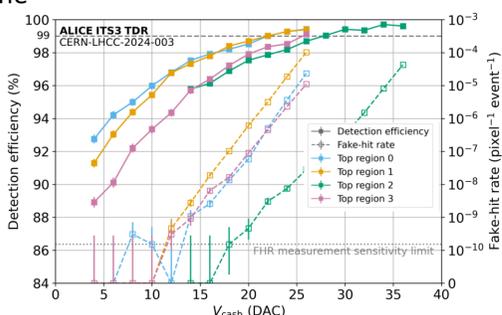
Extensive mass testing (120 chips from 20 wafers) to evaluate:

- Performance
- Production yield

First steps:

- Measurements of power net impedances
- Power ramp of the supplies

Detection efficiency and spatial resolution expected from MLR1 chips are confirmed.



Wafer	1-TOP	1-BOT	2-TOP	2-BOT	3-TOP	3-BOT	4-TOP	4-BOT	5-TOP	5-BOT	6-TOP	6-BOT	
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Conclusions and outlook

- ITS3 will be installed during LS3 to be ready for LHC Run 4 (2029-2032)
- First large-area stitched sensor produced
- Demonstrated bent MAPS operability [6], not shown
- Sensor qualification is on track:
 - Validated 65 nm CMOS process with MLR1 prototypes
 - Stitching qualification is ongoing

References

- ALICE Collaboration, Letter of Intent for an ALICE ITS Upgrade in LS3, 10.17181/CERN-LHCC-2019-018
- Shreyasi Acharya, et al., Upgrade of the ALICE Inner Tracking System during LS3: study of physics performance, <http://cds.cern.ch/record/2868015>
- Tower Semiconductor home page, <https://towersemi.com/>
- M. Šuljić, ALPIDE: the Monolithic Active Pixel Sensor for the ALICE ITS upgrade, <https://iopscience.iop.org/article/10.1088/1748-0221/11/11/C11025>
- G. Aglieri Rinella, et al., Digital pixel test structures implemented in a 65 nm CMOS process, <https://doi.org/10.1016/j.nima.2023.168589>
- ALICE ITS3 project, First demonstration of in-beam performance of bent Monolithic Active Pixel Sensors, <https://doi.org/10.1016/j.nima.2021.166280>